Special Issue

Top-Down Micro- or Nanofabrication and Its Applications

Message from the Guest Editors

This Special Issue of *Micromachines* focuses on top-down micro- and nanofabrication. It will serve as a platform for communication of the latest developments and innovations in top-down micro- and nanofabrication and/or their applications. Researchers are invited to contribute with manuscripts that address the various challenges and opportunities in this field. Contributions covering the following topics, in addition to any related to the topic of the Special Issue, are welcome:

- Precision machining;
- Laser machining;
- Die manufacturing;
- New lithographical methods;
- Manufacturing system/equipment and tools;
- Surface properties and characterization;
- Reliability, consistency, and metrology;
- Semiconductor/optical/bio/medical applications;
- Precision molding and forming;
- Non-traditional manufacturing technology.

Guest Editors

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Deadline for manuscript submissions

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You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

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